## 501.41175X00/340101349US1

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Applicant:

Hiroyuki NAKANO et al.

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Serial No.:

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Filed:

15 February 2002

For:

METHOD AND APPARATUS FOR PLASMA PROCESSING

Group:

1762

Examiner:

M. Padgett

Conf. No.:

7857

## PETITION FOR EXTENSION OF TIME

Mail Stop AF **EXPEDITED PROCESSING REQUESTED UNDER 37 CFR §1.116** Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

18 April 2005

Sir:

Applicant respectfully petitions for an extension of the shortened statutory period for response to the final Office Action mailed 18 November 2004 in connection with the above-identified application. A Form PTO-2038 authorizing payment of all fees required for entry of this paper is being filed concurrently herewith. Please charge any actual fee deficiency to ATS&K Deposit Account No. 01-2135 (as Case No. 501.41175X00).

Respectfully submitted,

04/20/2005 REONNER 60000017 10075244

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